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SERIAL NUMBER 10/665,982	FILING DATE 09/18/2003  RULE	CLASS 438	GROUP ART UNIT 1765	ATTORNEY DOCKET NO. MEMC 02-0051 (3032.1)
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## \*\* CONTINUING DATA \*\*\*\*\*

This appln claims benefit of 60/411,544 09/18/2002  
and claims benefit of 60/487,662 07/16/2003

EC

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

None/EC

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 12/11/2003

Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	STATE OR COUNTRY MO	SHEETS DRAWING 16	TOTAL CLAIMS 129	INDEPENDENT CLAIMS 8
35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged Examiner's Signature <i>Eve Chin</i>	Initials <i>EC</i>			

## ADDRESS

000321  
SENNIGER POWERS  
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## TITLE

Process for etching silicon wafers